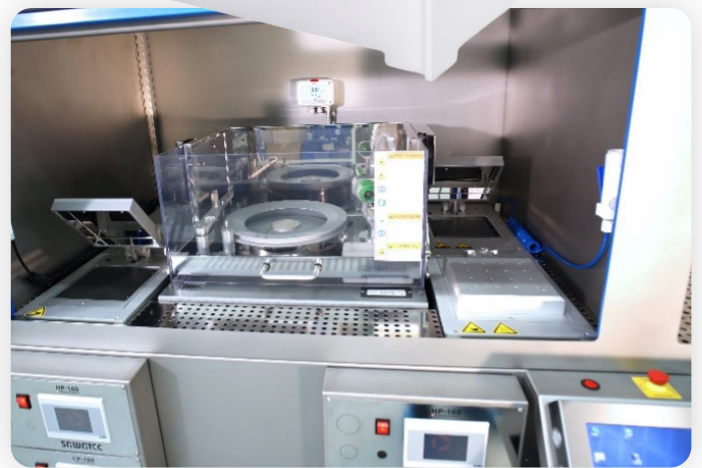


## ETCHING MODULE $\mu$ CHEM



The etching unit  $\mu$ Chem is a sufficient wet chemical process tool for all wet chemical process steps needed in the MEMS-, Semicon-, Optic- and Solar Industry. Because of the flexible arrangement and build-up, the etching system  $\mu$ Chem is the ideal tool either for industrial or R&D demands. The complete buildup of the system is made of plastics (PP white) to guarantee a maximal resistance against chemical attacks either of acids or bases. Following the German law of environmental protection, the system has a level controlled pan, which can be used for secure storing of chemicals or lab tools. Of course, customized solutions are available after clearing the technical details.

# ETCHING MODULE $\mu$ CHEM

## Data sheet

**Wafer Sizes:** up to 300mm

**Applications:** MEMS, CMOS, Sensor, PV, R&D or Production Type

### ETCHING MODULES

- Batch or Single Wafer Version available for Cleaning, Etching, Dissolving etc.
- Customized Chamber amount and Material Selection
- PLC controlled
- Touch Panel for easy operation

### RINSING MODULE

- Standard: Overflow Rinse,
- Optional: QDR, SRD

### General OPTIONS

- Automatic Handling (Ready for Robot Handling)
- Overflow circulation with filtration
- Ultra- or Mega sonic
- Internal Chemical Management
- Carrier Movement
- Integration of pre/post process cells possible
- Integration of Laminar-Flow-Units
- Execution as fume hood
- FM 4910 proofed material

### BUILD-UP

- Material: PP white
- Door material: PVC transparent
- PP plumbing, optional PVDF or PFA tube with PFA Flaretek Fittings
- HMI: Touch Panel

### OPERATING ELEMENTS

- All process operating elements are integrated into the front panel,
- All electrical and pneumatically components are integrated in an independent compartment in the back side service area,
- DIW- and N<sub>2</sub>-Spray gun integrated in the working surface

